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Sheet 1 of 1

Complete if Known

Application Number	10/086,652
Filing Date	February 28, 2002
First Named Inventor	Ashurst, William R.
Group Art Unit	1762
Examiner Name	To Be Assigned
Attorney Docket Number	02307V-121600US

U.S. PATENT DOCUMENTS

Examiner Initials *	Cite No. ¹	U.S. Patent Document		Name of Patentee or Applicant of Cited Document	Date of Publication of Cited Document MM-DD-YYYY	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		Number	Kind Code ² (if known)			
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OTHER PRIOR ART - NON PATENT LITERATURE DOCUMENTS

Examiner Initials *	Cite No. ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T ²
WN	AL	ASHURST, W. et al., "Dichlorodimethylsilane as an anti-stiction monolayer for MEMS: A comparison to the octadecyltrichlorosilane self assembled monolayer," Journal of Microelectromechanical Systems, 2001, pp. 41-49, Vol. 10(1).	
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Examiner Signature

W. R. Ashurst

Date Considered

10/31/03

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